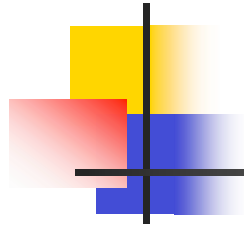


High performance thick-film pressure sensors on steel

**C. Jacq(1), T. Maeder(1), S. Martinerie(2),
G. Corradini(1), I. Saglini(1),
E. Carrenõ-Morelli(2), and P. Ryser(1)**

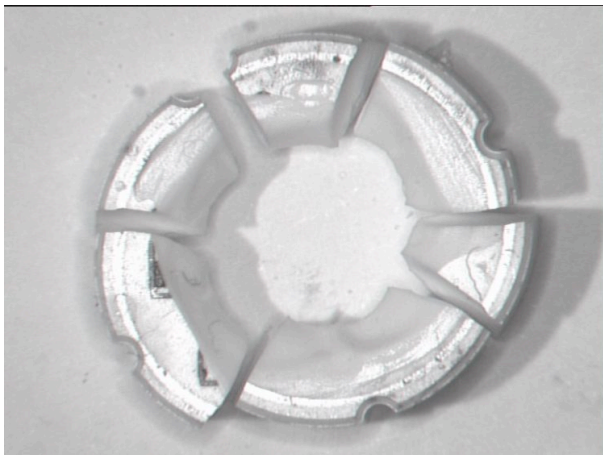
(1) EPFL – LPM, Lausanne, lpm.epfl.ch

(2) Haute école Valaisane (HEVs), Sion, Switzerland



Goal

- To develop high pressure sensors

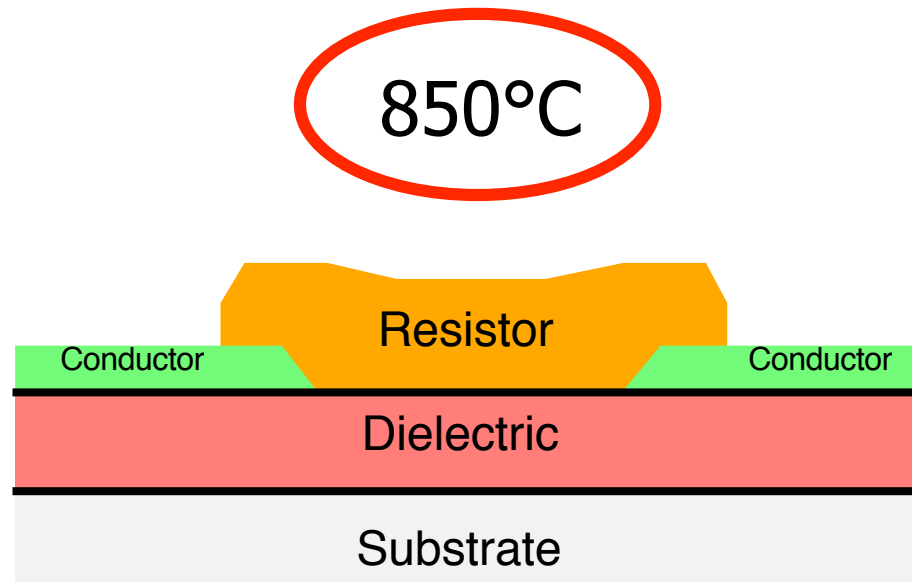


Ceramic membrane



Metallic membrane
assembly by welding

Standard thick-film (TF) technology



Standard TF
deposited on common
steel



2 routes

- High temperature resisting steel suitable with standard TF process

- High temperature TF system

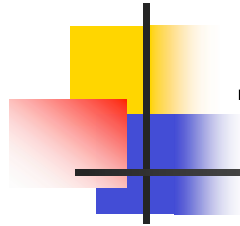


low temperature TF system

- Compatibility of thermal expansion
- Dielectric-resistor compatibility
- Adhesion
- Stability of the resulting circuits

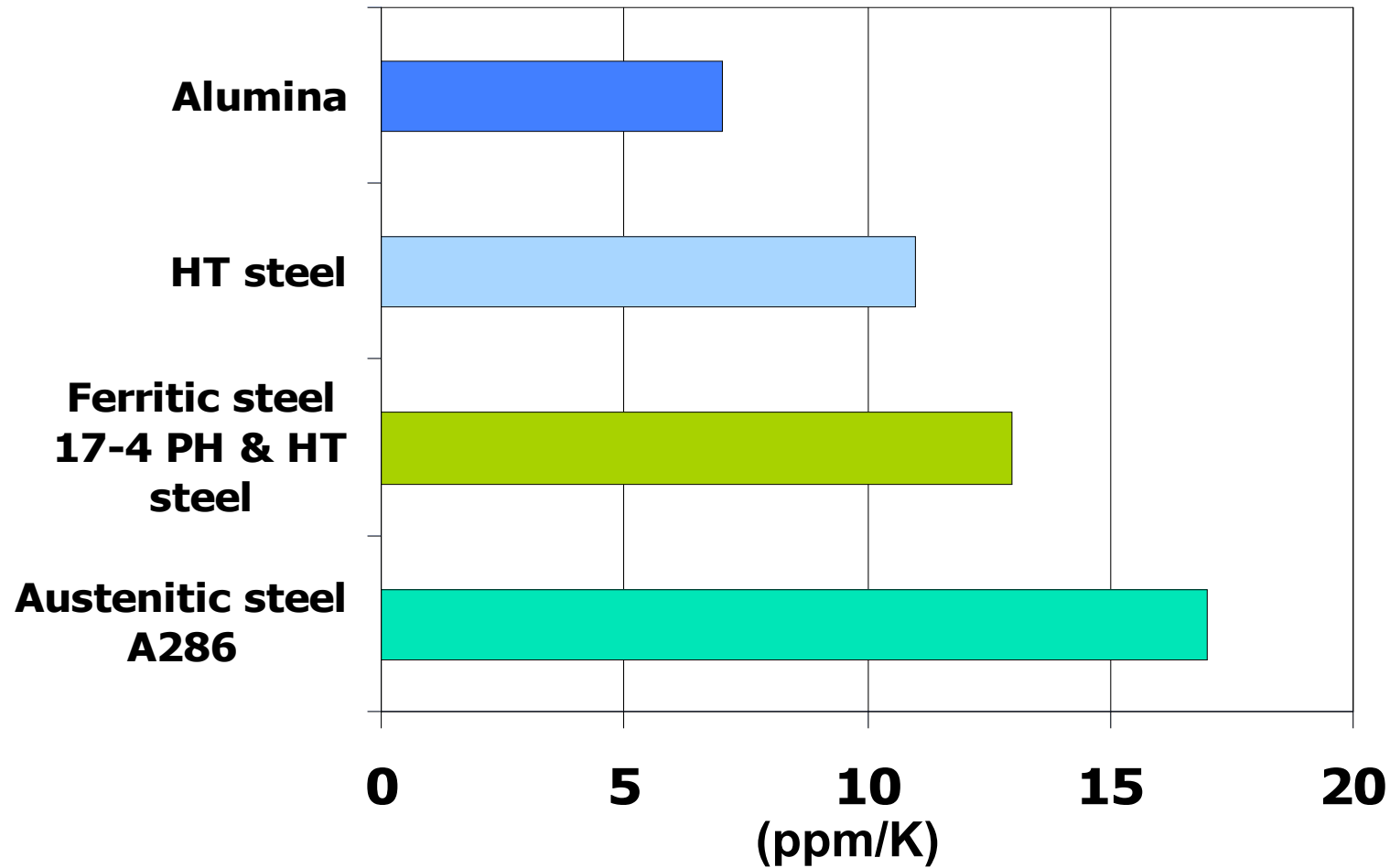
The substrates

	HT steel	A 286	17-4 PH	17-4 PH
manufacturing	machining	machining	-Machining(TP) -MIM(membrane), sintered@1340°C	-Machining(TP) -MIM(membrane), sintered@1350°C
Thermal treatment	-	solution treated:1h30@900°C Quenched:16h@730°C	-	-
Temperature process for Thick-system	850°C	625°C	625°C & 525°C	625°C & 525°C



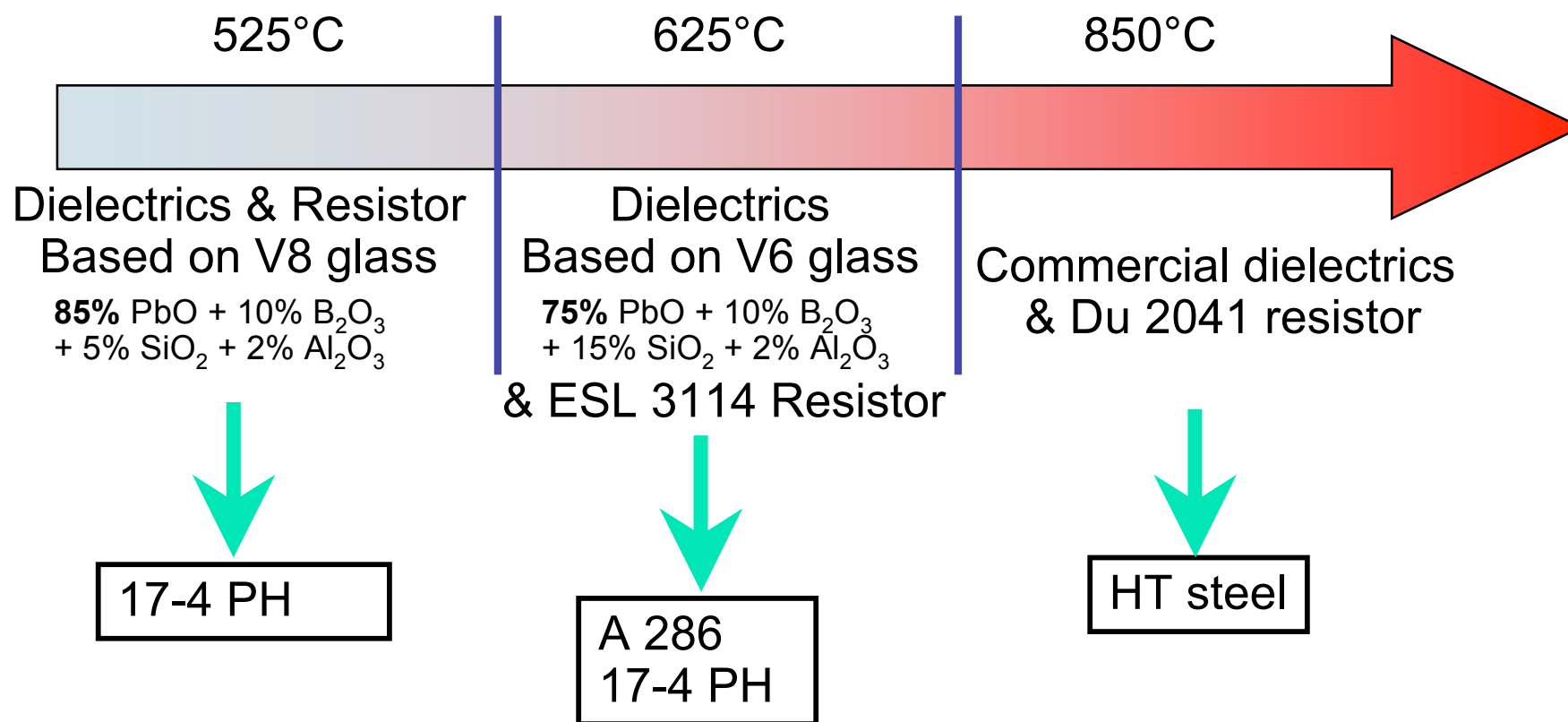
Thick-film system

TCE of tested Substrates

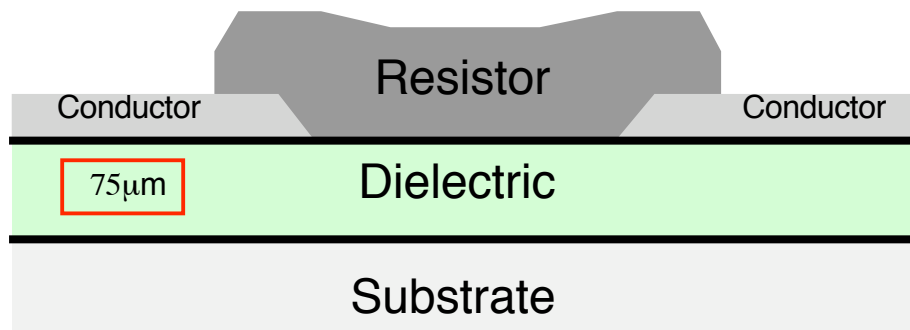


Thick film system

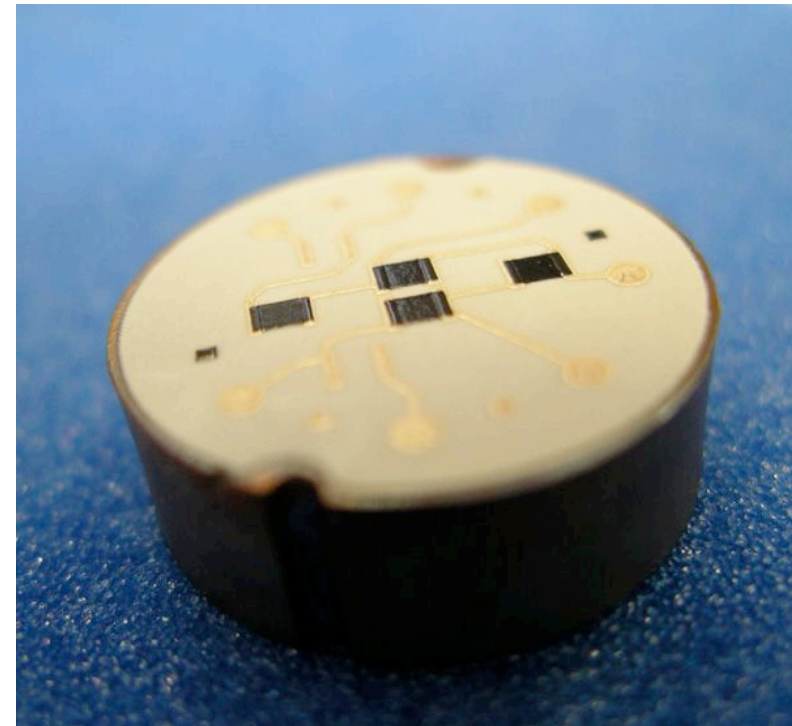
System Firing Temperature



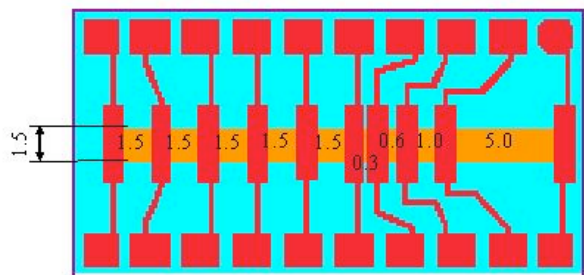
Screen-printing sequence



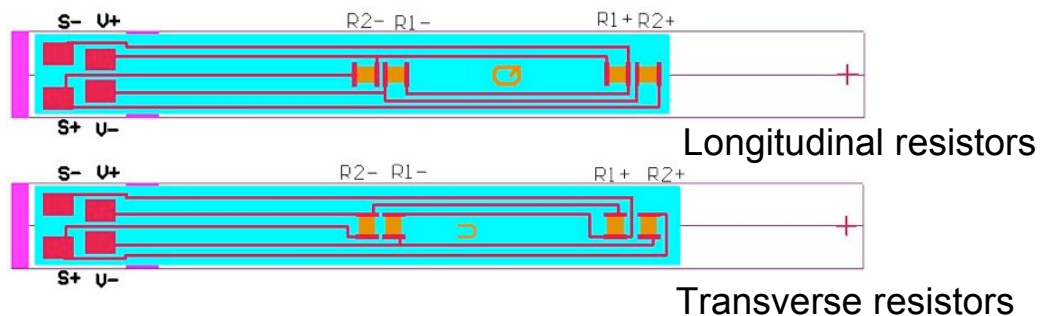
Basic structure



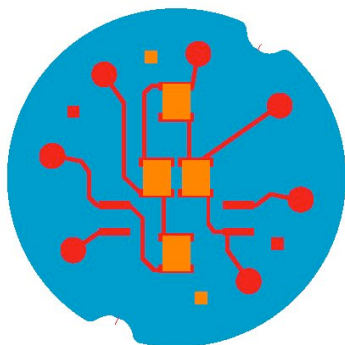
Samples for characterisation



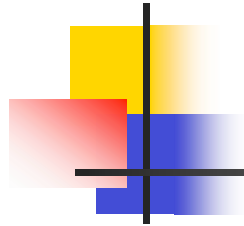
- Sheet resistance
- TCR measurement



- Gauge Factor measurement



- Response
- Drift



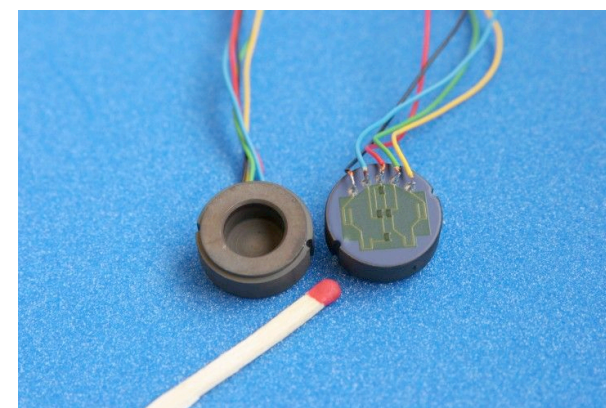
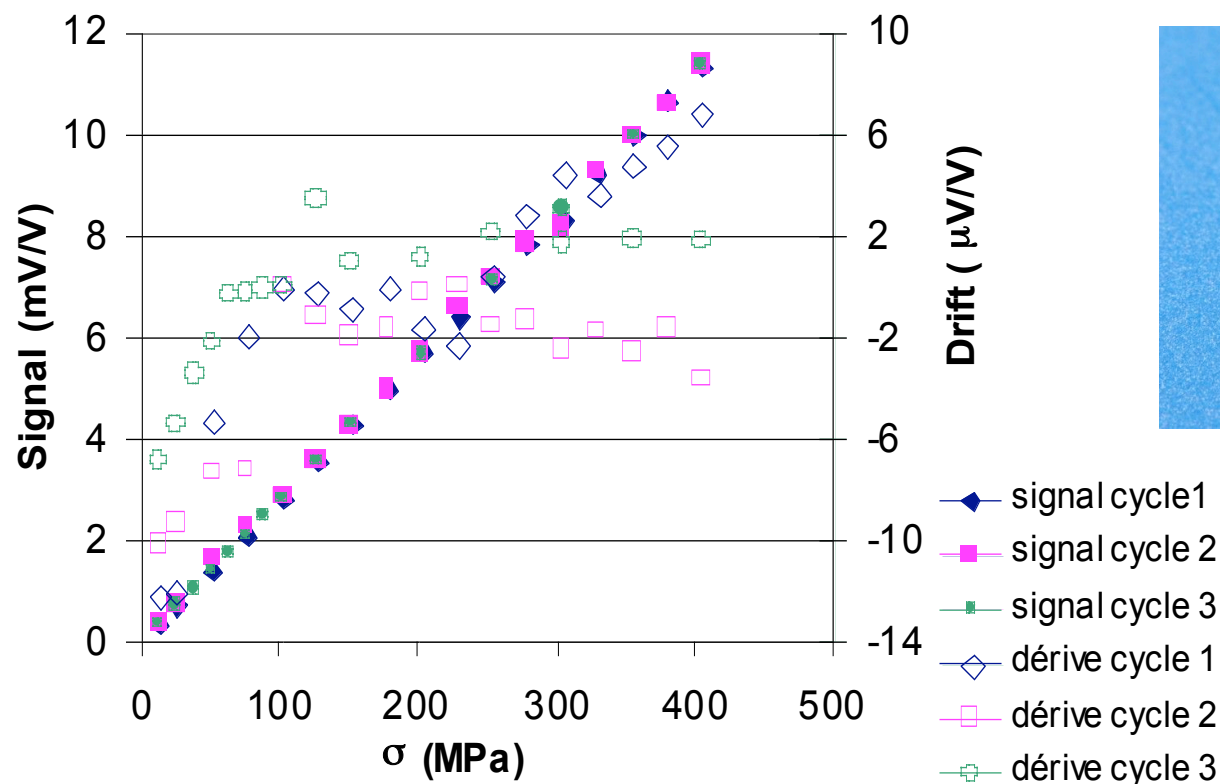
Electrical results

Dielectric Conductor Resistor	V6Q55 ESL 9912A ESL 3114	V8Q40 ESL 9912A:V8 V8 resistor
Res. Firing temperature	625°C	525°C
Sheet resistance (kΩ)	21±2 (Al ₂ O ₃ :11±1)	50±10 (Al ₂ O ₃ :19±5)
TCR (ppm/K)	13±6 (Al ₂ O ₃ :-220±15)	578±7 (Al ₂ O ₃ :363±8)
Gauge factor (longitudinal &transverse)	L:12.2±0.2 T:9.4±0.1 Al ₂ O ₃ : (L) 10.3±0.2 (T)7.7±0.2	L:23.5±0.2 T:18.9±0.2 Al ₂ O ₃ : (L) 23.0±0.3 (T)19.1±0.2



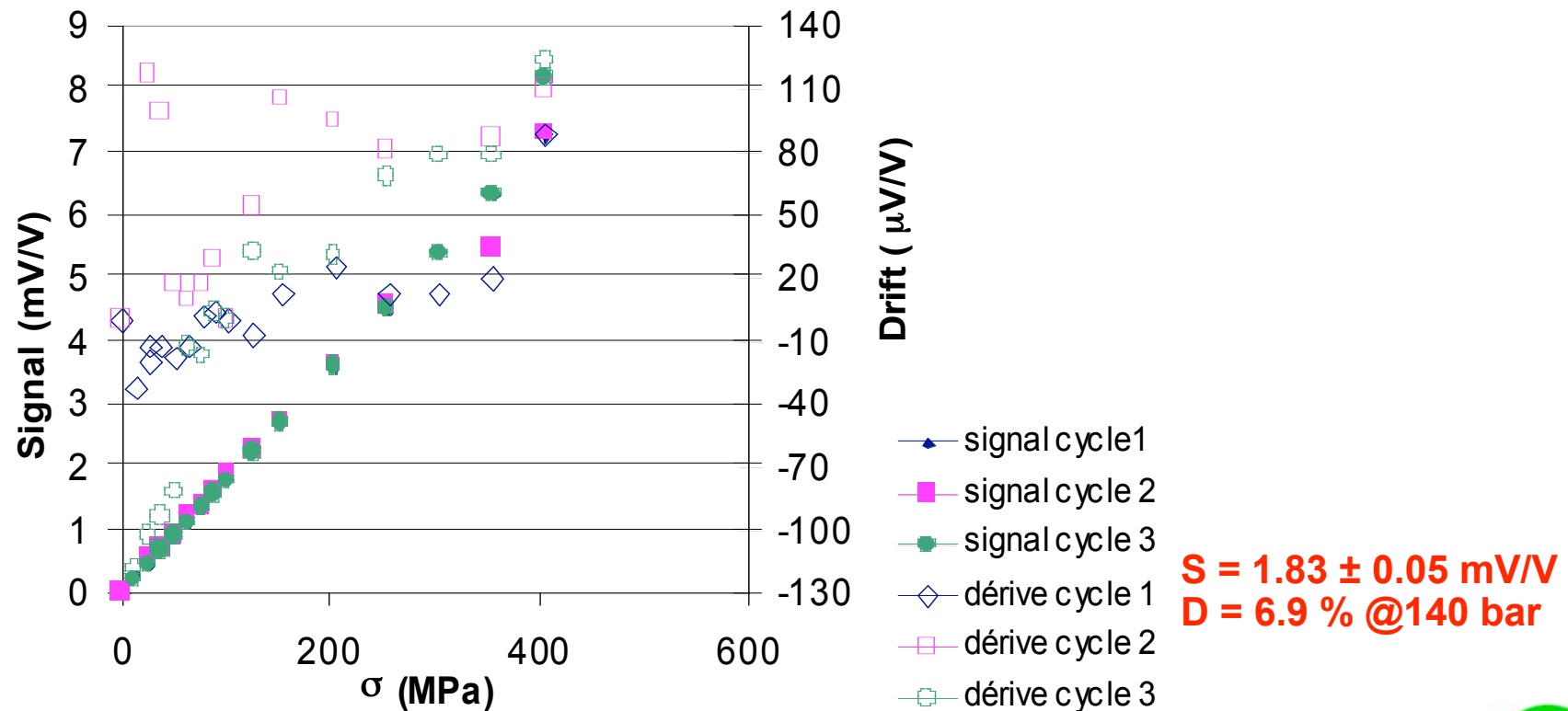
Performance of cells under pressure

■ HT cells (commercial TF system fired @ 850°C)



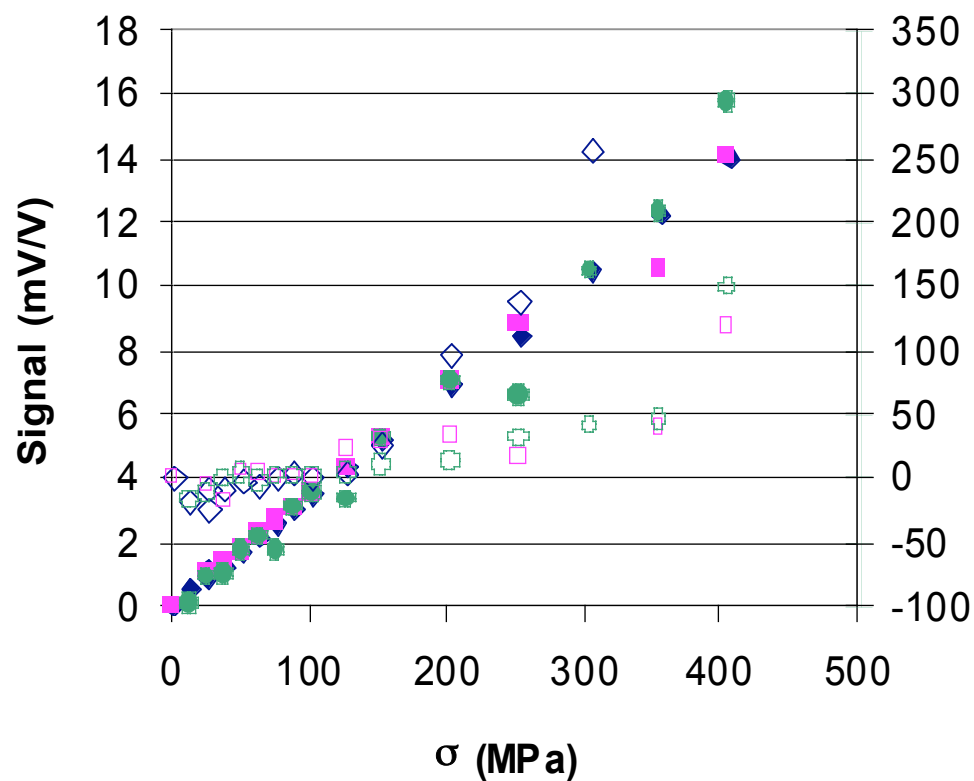
S = 2.839 ± 0.007 mV/V
D = 0.06 % @140 bar

A286 cells (commercial TF system fired @ 625°C)



17-4 PH cells (625°C TF system)

■ 17-4 PH sintered @ 1340°C

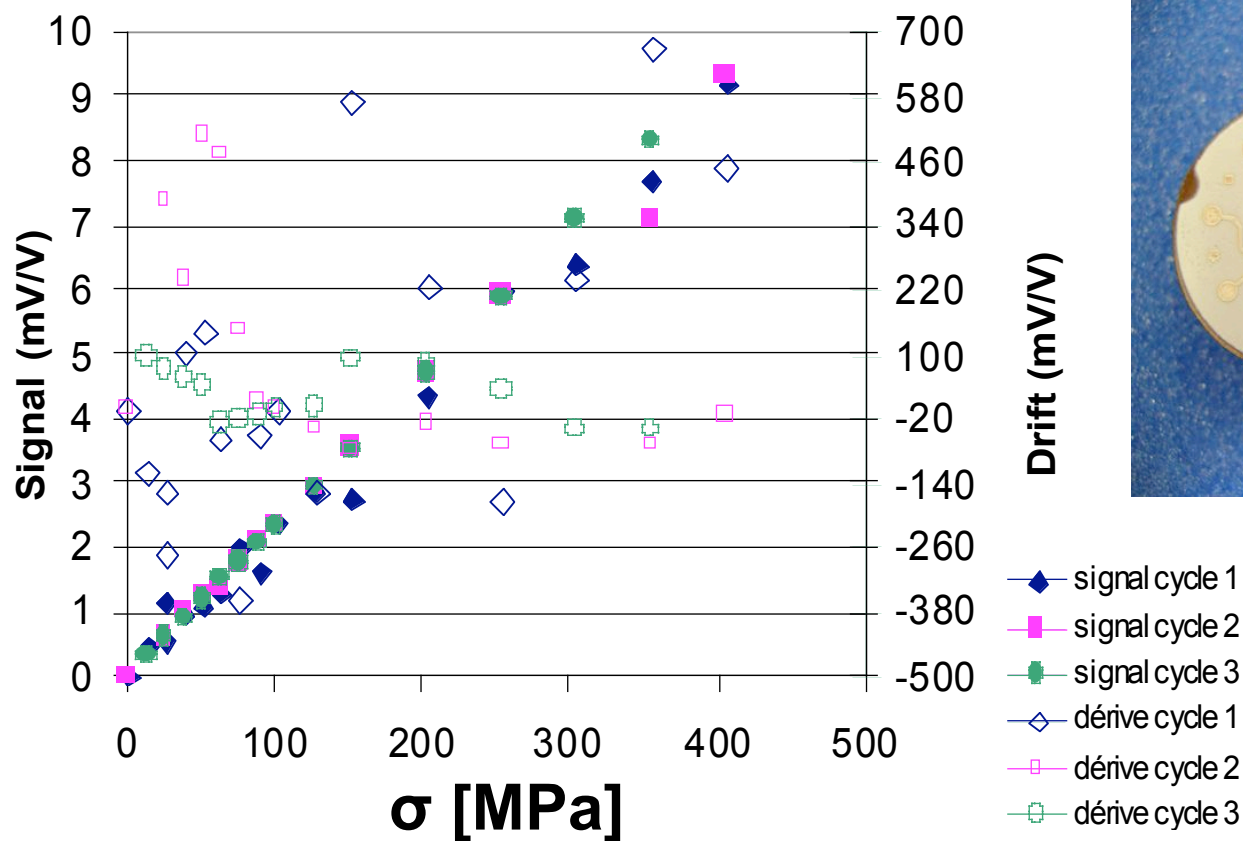


- ◆ signal cycle 1
- signal cycle 2
- signal cycle 3
- ◇ dérive cycle 1
- dérive cycle 2
- ⊕ dérive cycle 3

$S = 3.51 \pm 0.02$ mV/V
 $D = 4.2$ % @140 bar

17-4 PH cells (625°C TF system)

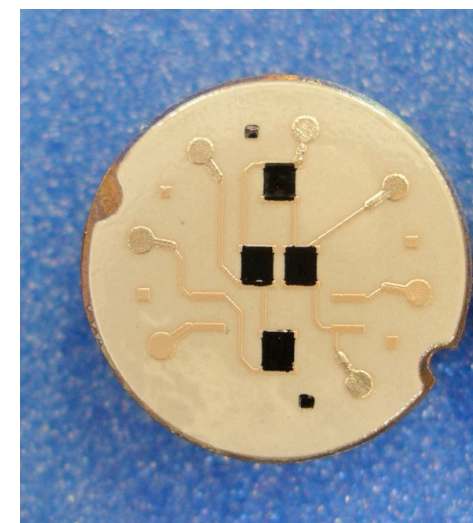
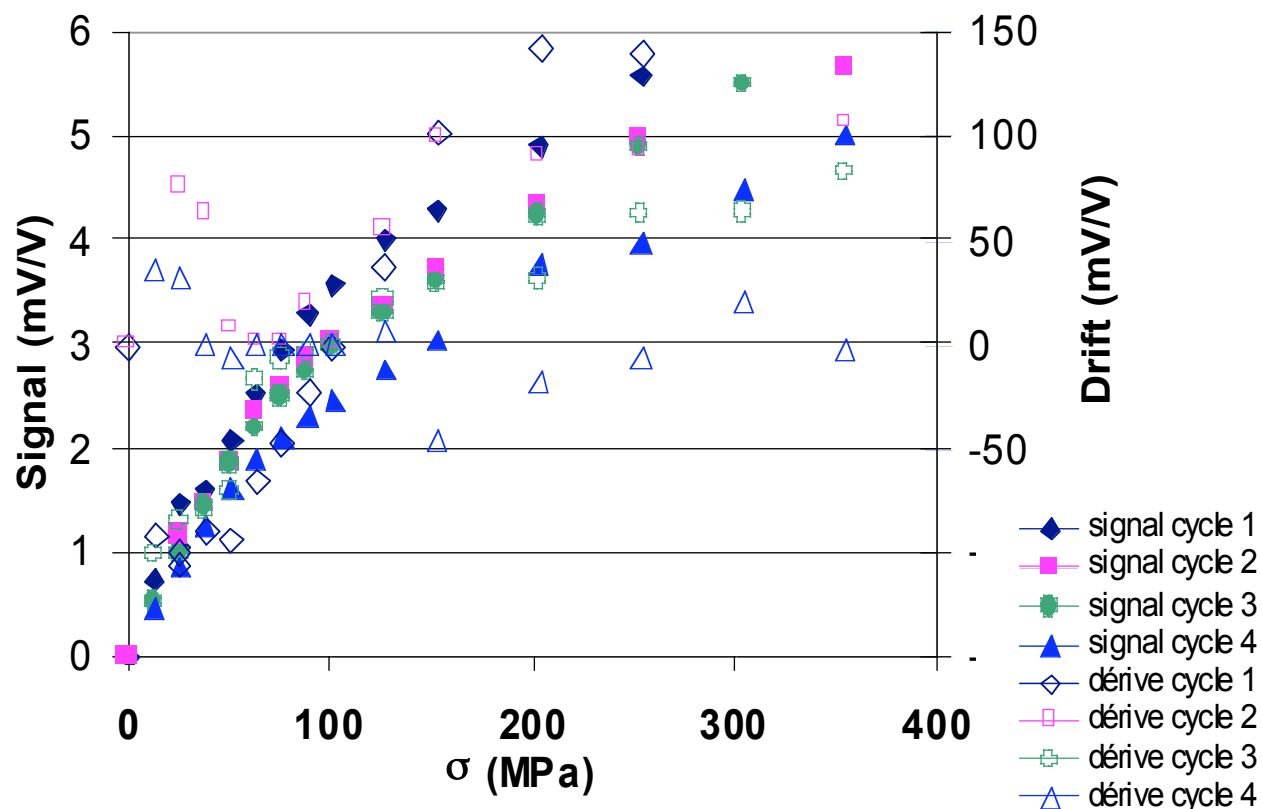
■ 17-4 PH sintered @ 1350°C



S = 2.37 ± 0.02 mV/V
D = 1.7 % @140 bar

17-4 PH cells (525°C TF system)

■ 17-4 PH sintered @ 1340°C

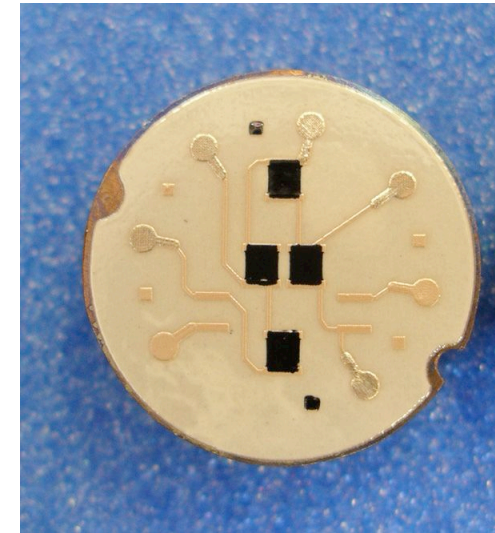
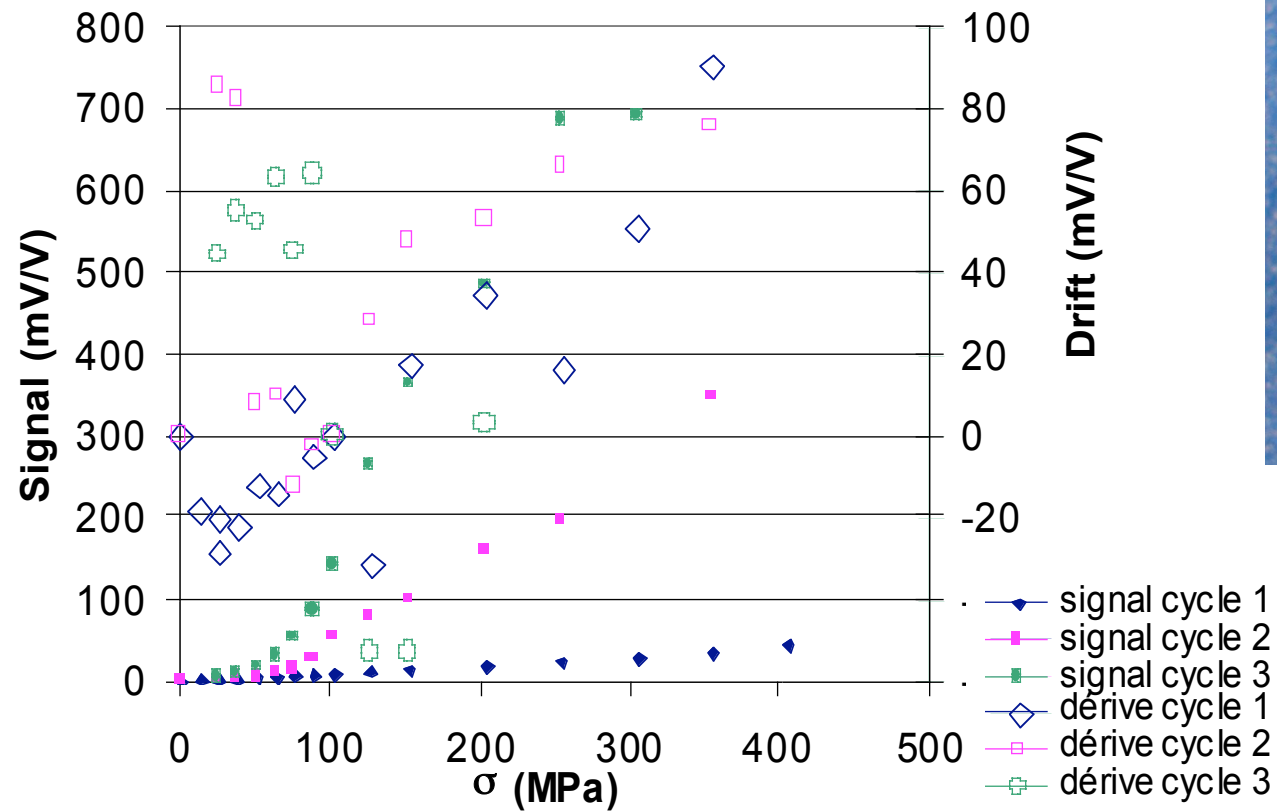


S = 3.2 ± 0.03 mV/V

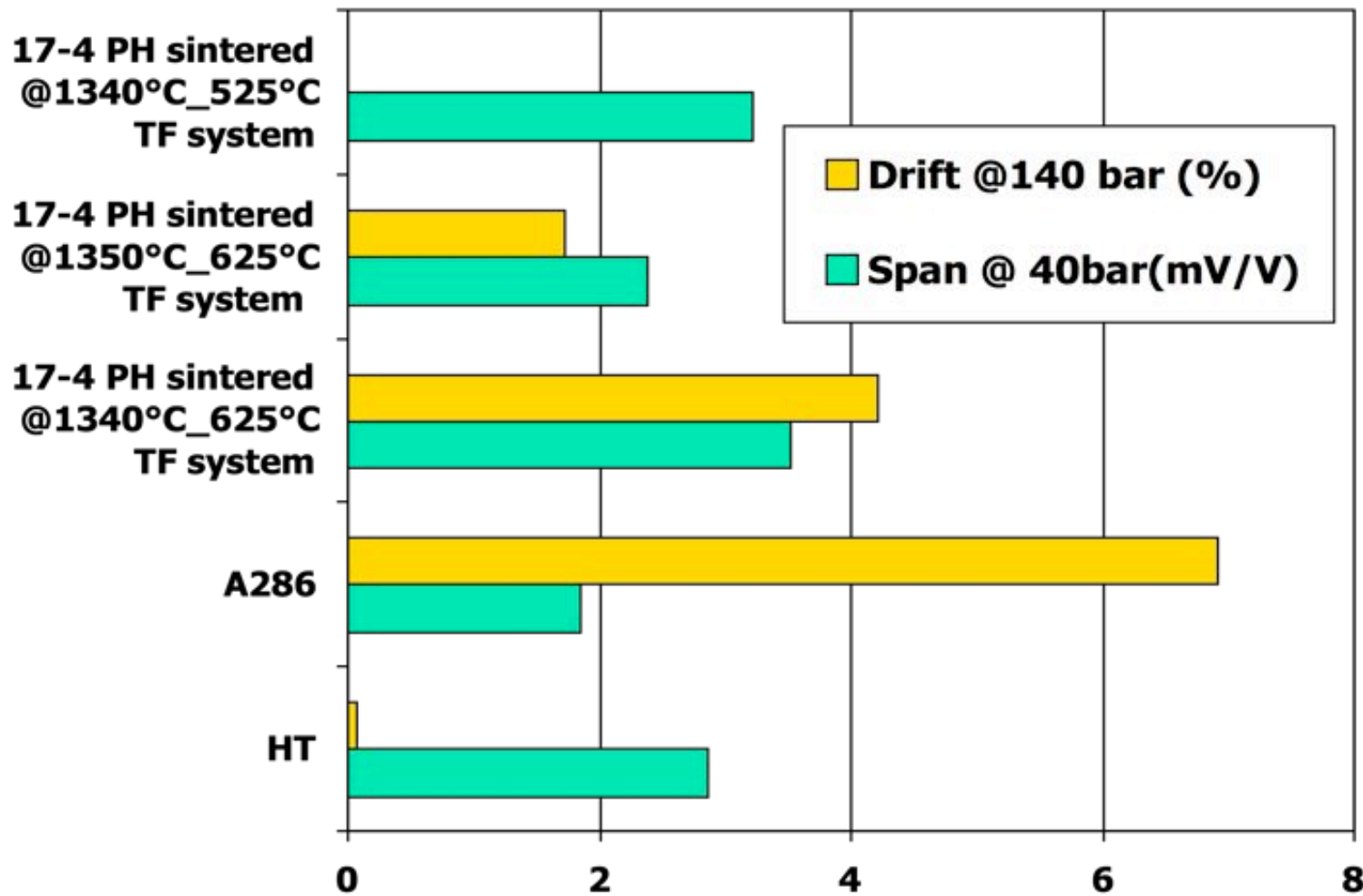
D = ...

17-4 PH cells (525°C TF system)

■ 17-4 PH sintered @ 1350°C

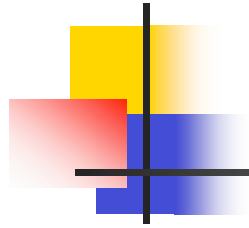


Summary



Conclusions and outlook

- Excellent results on HT steel with commercial TF system but too expensive
- Excellent electrical properties for semi-custom 625°C firing system on common high-strength steels. But stability under high loads must still be improved.
- Control of TCR of our resistors through additives (CuO, NiO, TiO₂, Sb₂O₃)
- Improve adhesion promoters
- Materials without Pb or precious metals



Hvala!

Thank you for your
attention!